



Docket No.: M4065.0466/P466
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Neal Rueger

Application No.: 09/938,644

Confirmation No.:

Filed: August 27, 2001

Art Unit: 1765

For: METHOD AND APPARATUS FOR
MICROMACHINING USING A
MAGNETIC FIELD AND PLASMA
ETCHING

Examiner: T. Mackey

INFORMATION DISCLOSURE STATEMENT (IDS)

MS RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO/SB/08. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

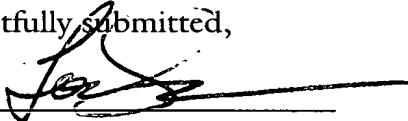
In accordance with 37 C.F.R. § 1.97(g), the filing of this Information Disclosure Statement shall not be construed to mean that a search has been made or that no other material information as defined in 37 C.F.R. § 1.56(a) exists. In accordance with 37 C.F.R. § 1.97(h), the filing of this Information Disclosure statement shall not be construed to be an admission that any patent, publication or other information referred to therein is "prior art" for this invention unless specifically designated as such.

It is submitted that the Information Disclosure Statement is in compliance with 37 C.F.R. §1.98 and the Examiner is respectfully requested to consider the listed references.

The Director is hereby authorized to charge any deficiency in the fees filed, asserted to be filed or which should have been filed herewith (or with any paper hereafter filed in this application by this firm) to our Deposit Account No. 04-1073, under Order No. M4065.0466/P466. A duplicate copy of this paper is enclosed.

Dated: March 2, 2004

Respectfully submitted,

By 

Thomas J. D'Amico, Registration No.: 28,371
Ryan H. Flax, Registration No.: 48,141
DICKSTEIN SHAPIRO MORIN &
OSHINSKY LLP
2101 L Street NW
Washington, DC 20037-1526
(202) 785-9700
Attorney for Applicant



MAR 02 2004

PTO/SB/08a/b (08-03)

Approved for use through 07/31/2006. OMB 0651-0031
U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

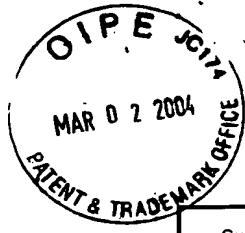
Substitute for form 1449A/B/PTO				Complete if Known	
				Application Number	09/938,644-Conf. #1172
				Filing Date	August 27, 2001
				First Named Inventor	Neal Rueger
				Art Unit	1765
				Examiner Name	T. Mackey
Sheet	1	of	2	Attorney Docket Number	M4065.0466/P466

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
A	5,976,347	11/1999	Wakabayashi et al.		
B	6,103,399	8/2000	Smela et al.		
C	5,972,193	10/1999	Chou et al.		

FOREIGN PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)			
					T ⁶

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹ Applicant's unique citation designation number (optional). ² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

NON PATENT LITERATURE DOCUMENTS					
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.			T ²
C1		MARC SCHAEPKENS et al.; "Asymmetric microtrenching during inductively coupled plasma oxide etching in the presence of a weak magnetic field", Applied Physics Letters, Vol. 72, Number 11, March 16, 1998.			
C2		K. DONOHOE; "Aspect Ratio-Plasma Effects" March 14, 2000.			
C3		"Introduction to Microengineering, Mask Design", http://www.dbanks.demon.co.uk/ueng/maskdes.html accessed July 3, 2001.			
C4		"Introduction to Microengineering, LIGA", http://www.dbanks.demon.co.uk/ueng/liga.html accessed July 3, 2001.			
C5		"Introduction to Microengineering, Excimer laser micromachining", http://www.dbanks.demon.co.uk/ueng/excimerum.html accessed July 3, 2001.			
C6		"Introduction to Microengineering, Wafer bonding", http://www.dbanks.demon.co.uk/ueng/waferbond.html accessed July 3, 2001.			
C7		"Introduction to Microengineering, Electrochemical etching of silicon", http://www.dbanks.demon.co.uk/ueng/electrochem.html accessed July 3, 2001.			
C8		"Introduction to Microengineering, Surface micromachining", http://www.dbanks.demon.co.uk/ueng/surfum.html accessed July 3, 2001.			
C9		"Introduction to Microengineering, Basic Structures", http://www.dbanks.demon.co.uk/ueng/sistruct.html accessed July 3, 2001.			
C10		"Introduction to Microengineering, Lift off", http://www.dbanks.demon.co.uk/ueng/liftoff.html accessed July 3, 2001.			
C11		"Introduction to Microengineering, Dry Etching", http://www.dbanks.demon.co.uk/ueng/dryetch.html accessed July 3, 2001.			
C12		"Introduction to Microengineering, Wet etching", http://www.dbanks.demon.co.uk/ueng/wetetch.html accessed July 3, 2001.			
C13		"Introduction to Microengineering, Thin films", http://www.dbanks.demon.co.uk/ueng/Thinfilms.html accessed July 3, 2001.			



PTO/SB/08a/b (08-03)

Approved for use through 07/31/2006. OMB 0651-0031

U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/B/PTO				Complete if Known	
				Application Number	09/938,644-Conf. #1172
				Filing Date	August 27, 2001
				First Named Inventor	Neal Rueger
				Art Unit	1765
				Examiner Name	T. Mackey
Sheet	2	of	2	Attorney Docket Number	M4065.0466/P466

	C14	"Introduction to Microengineering, Basic techniques", http://www.dbanks.demon.co.uk/ueng/sitech.html accessed July 3, 2001.	
	C15	"Integrated MicroElectroMechanical Systems", http://www.mdl.sandia.gov/micromachine/integrated.html accessed July 3, 2001.	
	C16	"Summit Technology", http://www.mdl.sandia.gov/micromachine/trilevel.html accessed July 3, 2001.	
	C17	"MEMS Overview", http://www.mdl.sandia.gov/micromachine/overview.html accessed July 3, 2001.	
	C18	"Vision for MEMS", http://www.mdl.sandia.gov/micromachine/vision.html accessed July 3, 2001.	
	C19	PHILIP BALL; "Honey, I shrunk the cogs", http://www.nature.com/nsu/010111/010111-3.html July 12, 2001.	

Examiner Signature	Date Considered
--------------------	-----------------

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Applicant's unique citation designation number (optional). ²Applicant is to place a check mark here if English language Translation is attached.